

| | | | |
|---|--|---|------------|
| FORM PTO-1449 (Rev. 2-32) | U.S. Department of Commerce Patent and Trademark Office | Atty. Docket No. 03-06 | Serial No. |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary) | | Applicant: Harry Levinson and Thomas White | |
| | | Filing Date: January 12, 2004 | Group: |

U.S. PATENT DOCUMENTS

| Examiner Initial | Document Number | Date | Name | Class | Subclass | Filing Date if Appropriate |
|---------------------|-----------------|------|------|-------|----------|-------------------------------|
| | | | | | | |
| | | | | | | |
| | | | | | | |

FOREIGN PATENT DOCUMENTS

| | Document Number | Date | Country | Class | Subclass | Translation | |
|--|-----------------|------|---------|-------|----------|-------------|----|
| | | | | | | Yes | No |
| | | | | | | | |
| | | | | | | | |
| | | | | | | | |

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc).

| | | |
|--|--|--|
| | | A. Mikkelsen et al., <i>EUVL Mask Flatness and Electrostatic Chucking Analysis</i> , Presented at the 47 th International Conference on Electron, Ion and Photon Beam Technology and Nanofabrication (Tampa, FL) and submitted to the <i>Journal of Vacuum Science and Technology B</i> , Nov/Dec, 2003 |
| | | |
| | | |

| | |
|--------------------------|---------------------------|
| EXAMINER Danny Nguyen | DATE CONSIDERED 8/7/06 |
|--------------------------|---------------------------|

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication.